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(12) **United States Design Patent**
Kato et al.

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(54) **VACUUM PROCESSING EQUIPMENT CONFIGURATION**

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(73) Assignee: **Hitachi, Ltd.**, Tokyo (JP)

(**) Term: **14 Years**

(21) Appl. No.: **29/099,072**

(22) Filed: **Jan. 12, 1999**

Related U.S. Application Data

(63) Continuation-in-part of application No. 09/061,062, filed on Apr. 16, 1998, now Pat. No. 5,950,330, which is a continuation of application No. 08/882,731, filed on Jun. 26, 1997, now Pat. No. 5,784,799, which is a division of application No. 08/593,870, filed on Jan. 30, 1996, now Pat. No. 5,661,913, which is a continuation of application No. 08/443,039, filed on May 17, 1995, now Pat. No. 5,553,396, which is a division of application No. 08/302,443, filed on Sep. 9, 1994, now Pat. No. 5,457,896, which is a continuation of application No. 08/096,256, filed on Jul. 26, 1993, now Pat. No. 5,349,762, which is a continuation of application No. 07/751,951, filed on Aug. 29, 1991, now Pat. No. 5,314,509.

(30) **Foreign Application Priority Data**

Aug. 22, 1990 (JP) 1-225321

(51) **LOC (7) Cl.** **15-05**
(52) **U.S. Cl.** **D32/1**
(58) **Field of Search** 34/406, 229, 92, 34/228; 134/902

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(57) **CLAIM**

The ornamental design for a vacuum processing equipment configuration, as shown and described.

DESCRIPTION

FIG. **1** is front, top and left side perspective view of cassettes storage eguipment in relation to a conveyor equipped robot and load and unload chambers showing our new design;
FIG. **2** is a top plan view;
FIG. **3** is a front side elevational view;
FIG. **4** is a right side elevational view;
FIG. **5** is a rear side elevational view;
FIG. **6** is a left side elevational view;
FIG. **7** is a bottom plan view; and,
FIG. **8** is a right side elevational view along line **8—8** of FIG. **2**.
The details shown in broken lines in all views is for illustrative purposes only and form no part of the claimed design.

1 Claim, 5 Drawing Sheets

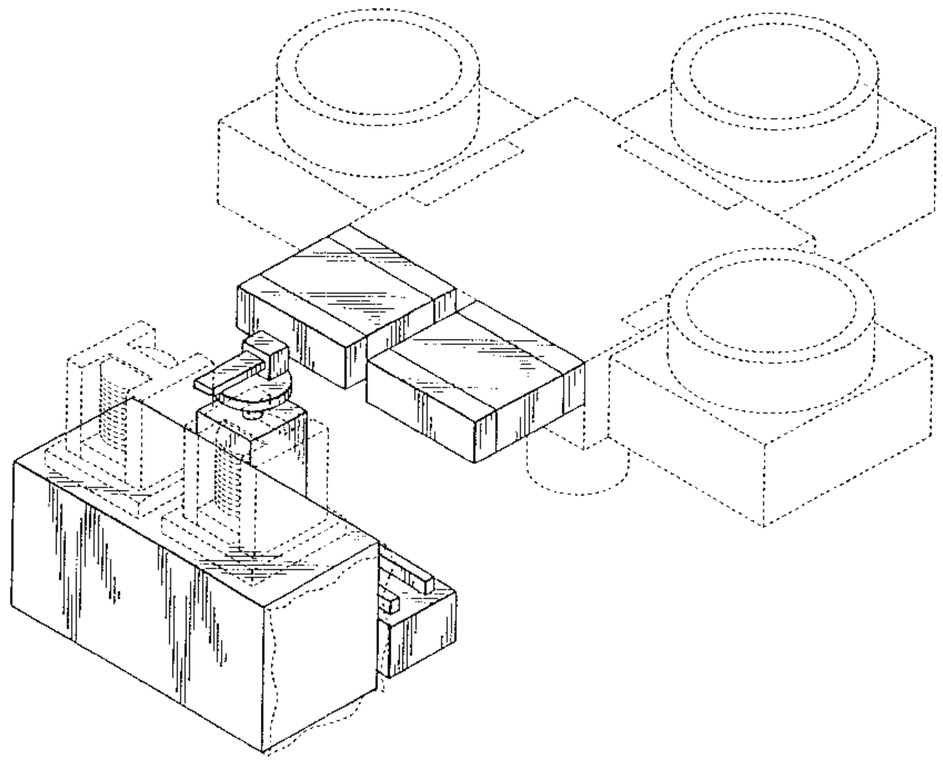

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FIG. 1

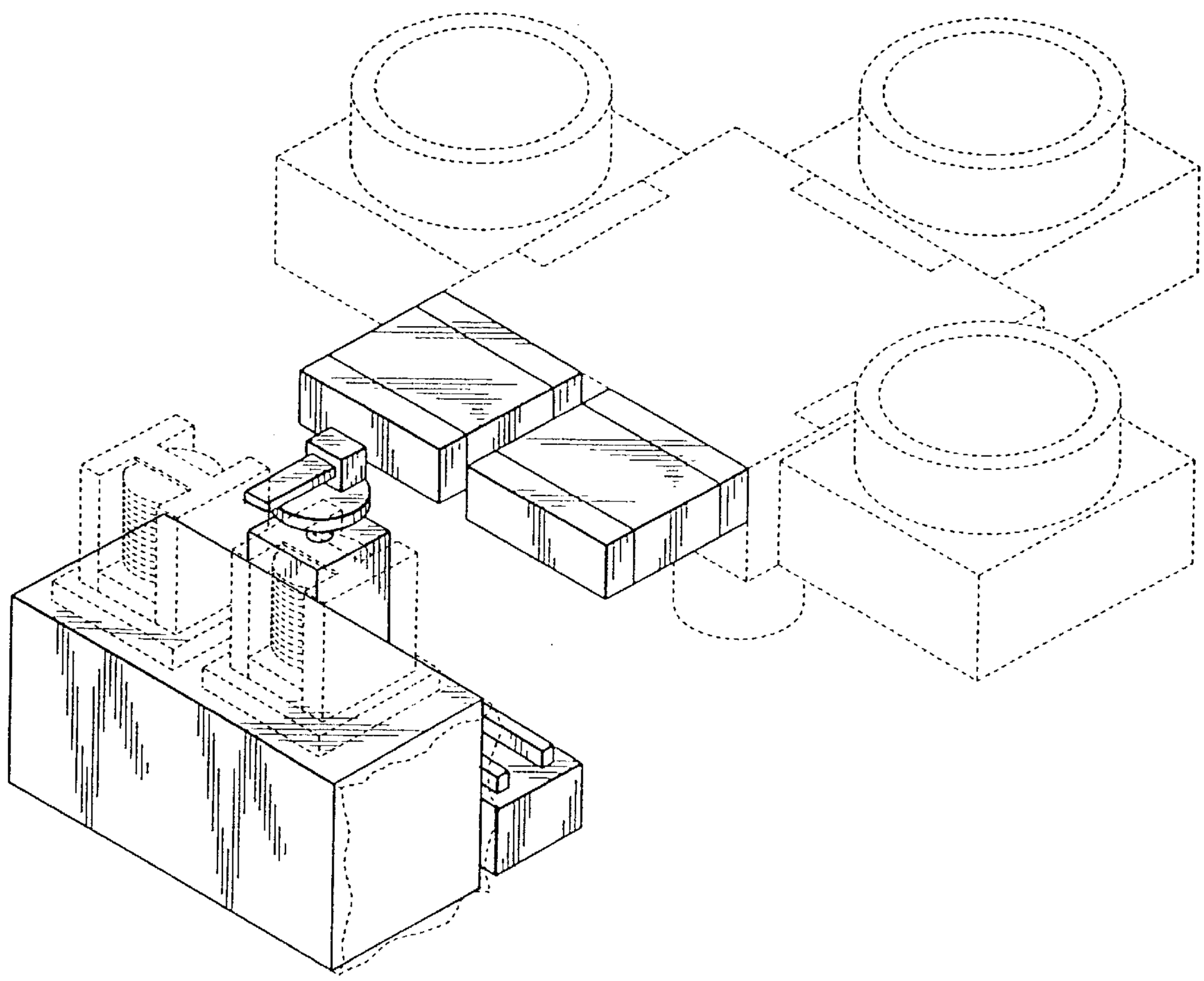

FIG. 2

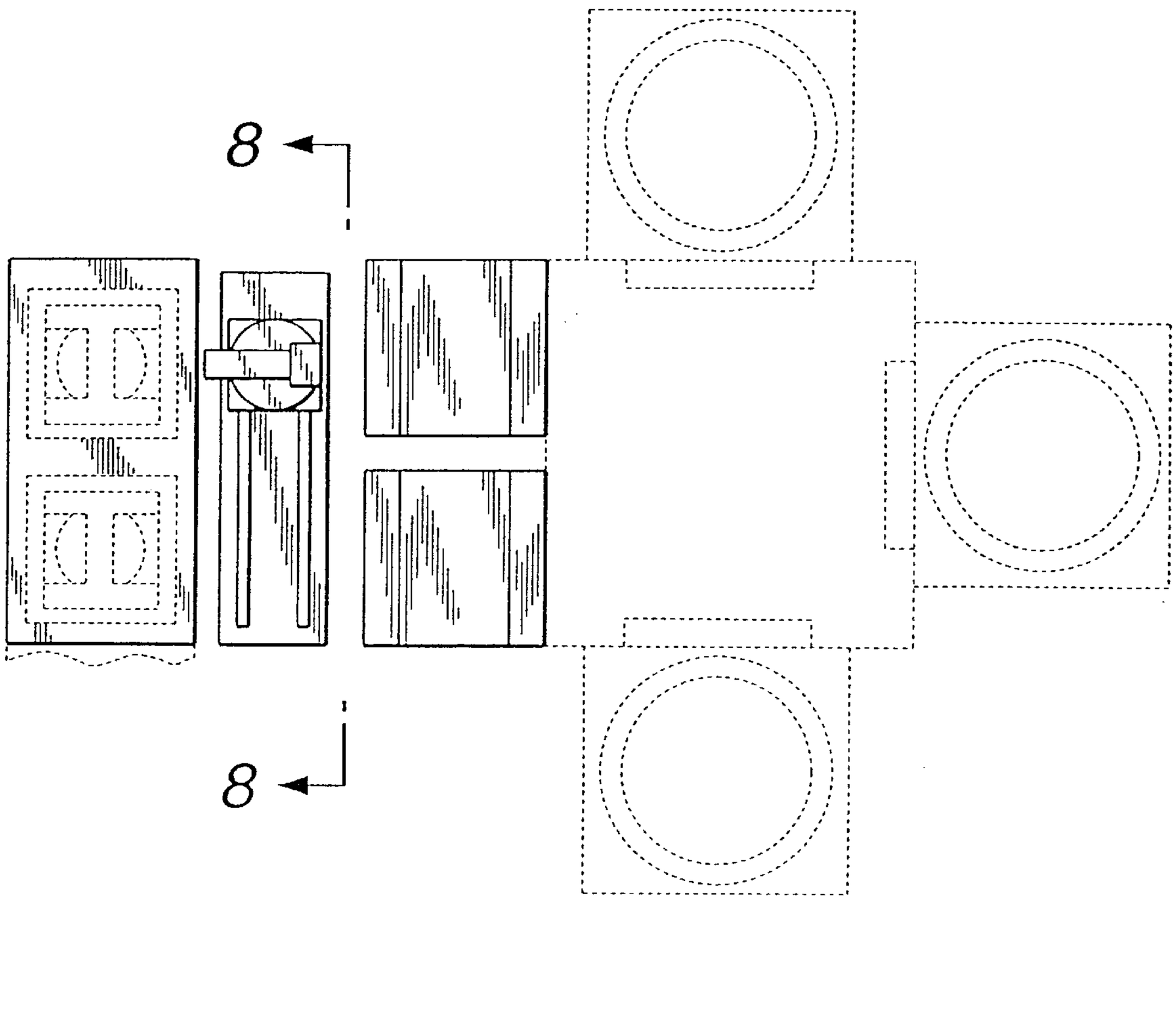

FIG. 3

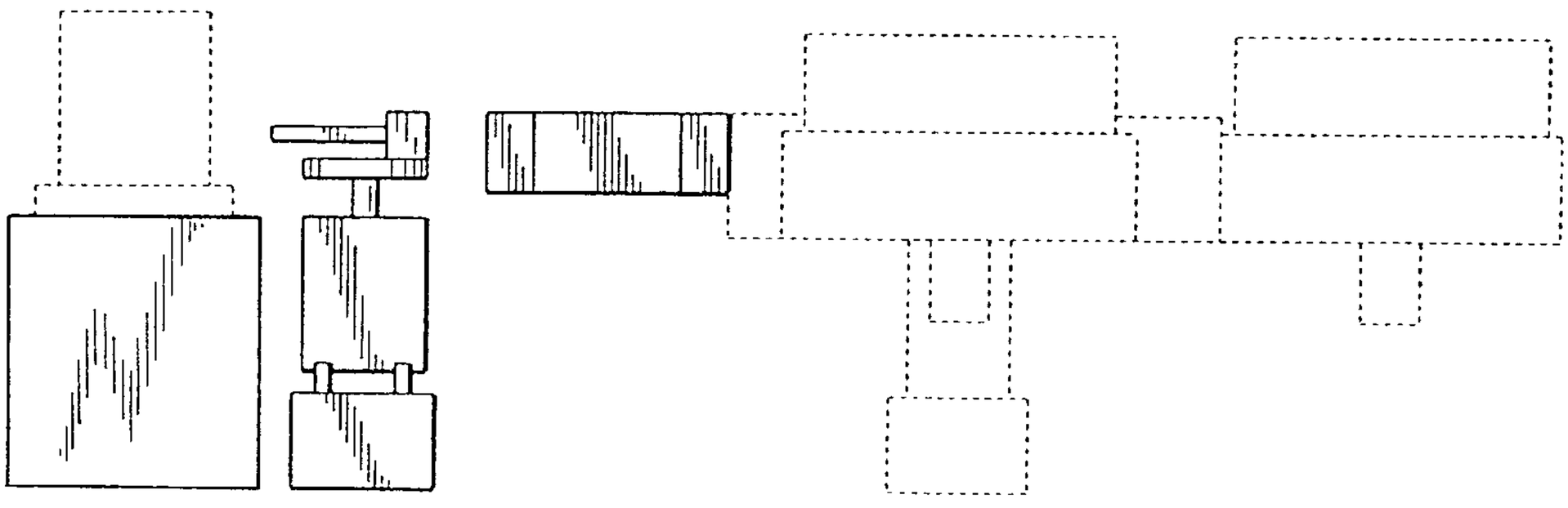

FIG. 4

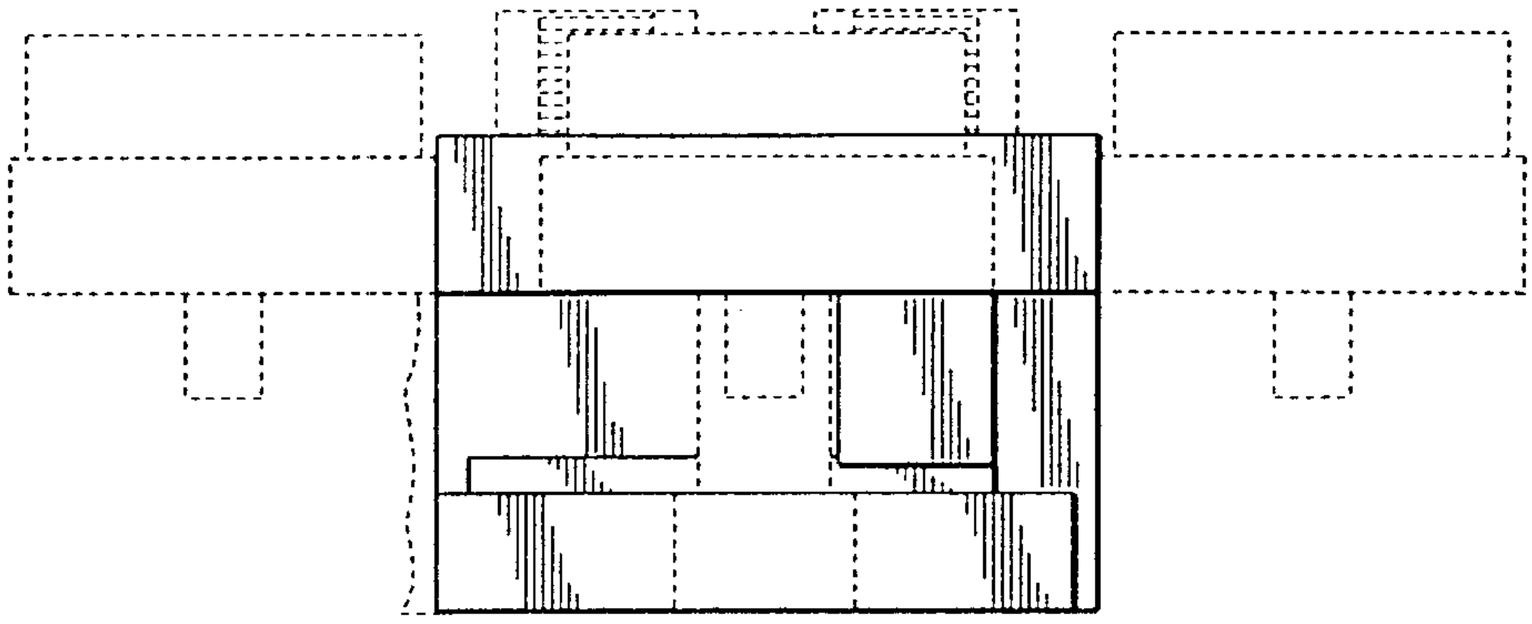

FIG. 5

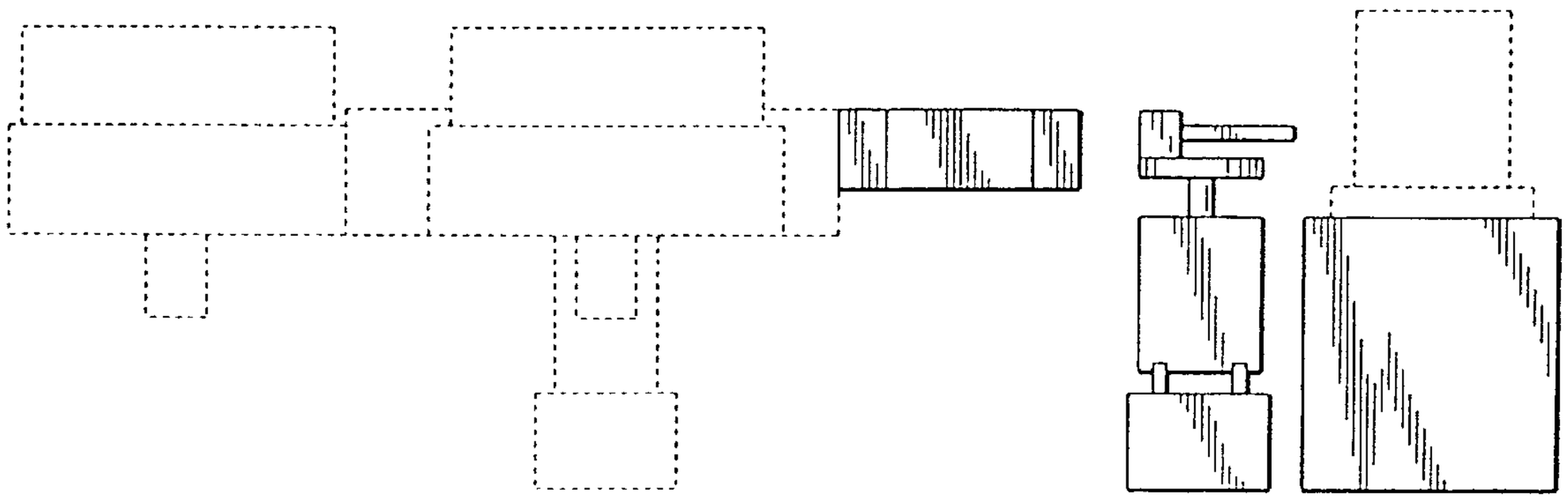

FIG. 6

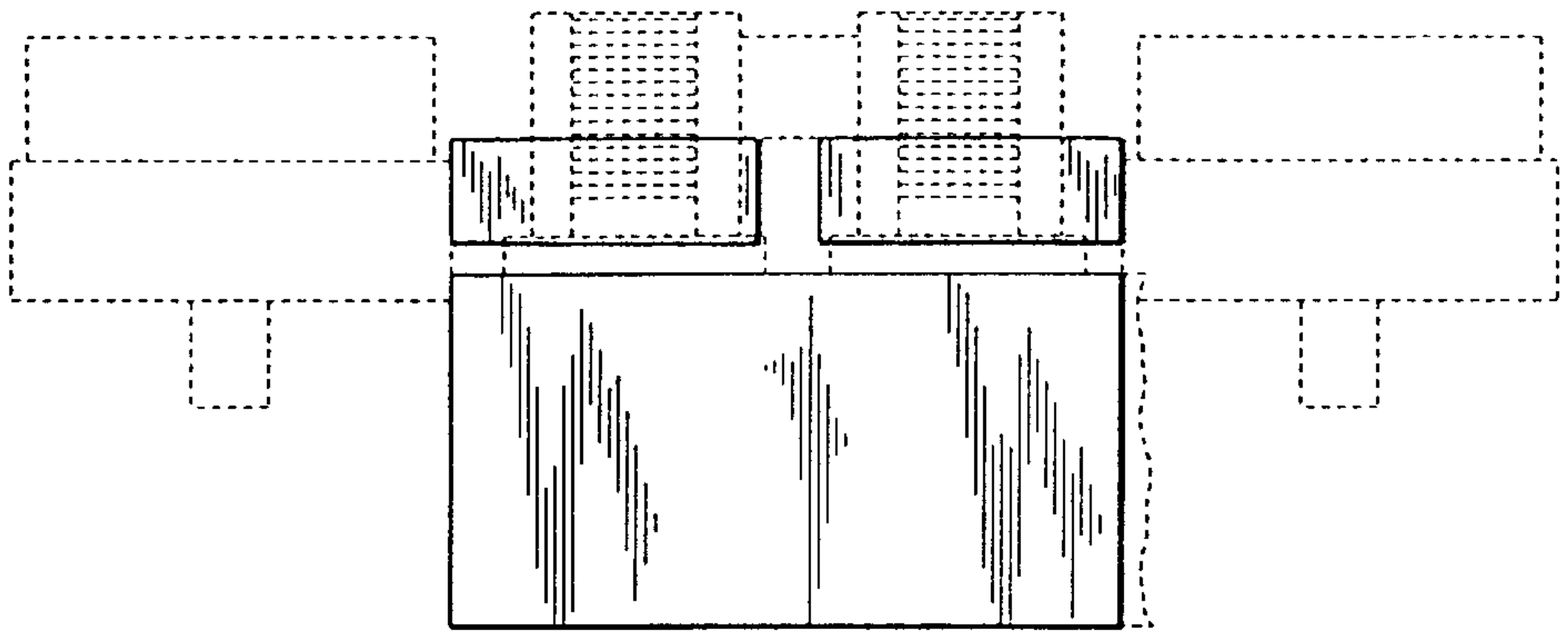

FIG. 7

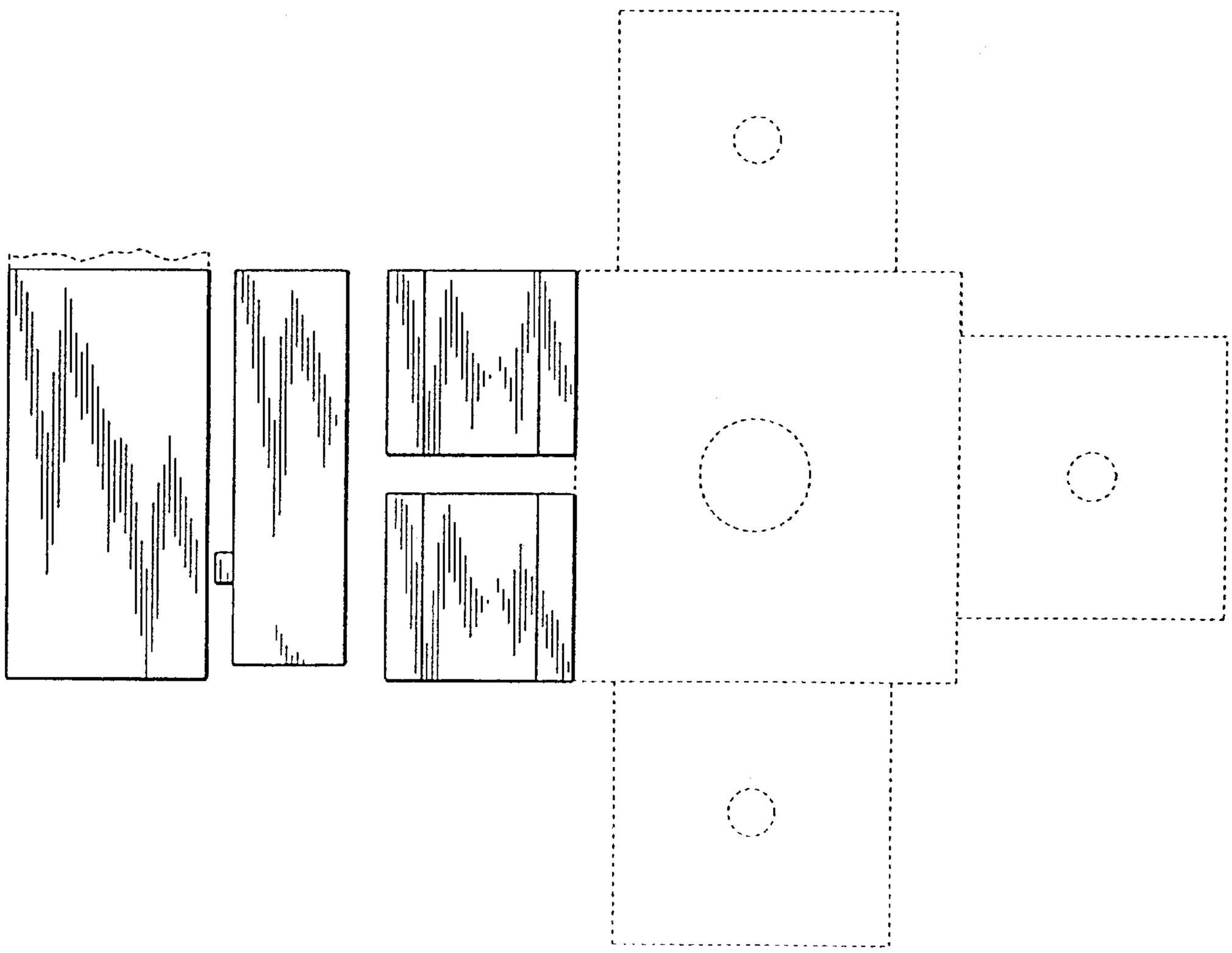

FIG. 8